

0321.68095



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Yeshaiahu Fainman )

Serial No.: 10/521,425 )

Filed: January 14, 2005 )

For: HOLOGRAPHICALLY DEFINED )  
SURFACE MASK ETCHING METHOD )  
AND ETCHED OPTICAL STRUCTURES )

Group Art Unit: )

I hereby certify that this paper is being deposited with  
the United States Postal Service as first class mail in an  
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Patents, Washington, D.C. 20231, on this date.

3/9/05

Registration No. 3C132

PRELIMINARY AMENDMENT

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Washington, D.C. 20231

Dear Sir:

Prior to examination of this application, please amend the application as follows: